Se	earch	Notes	

Application/Control No.	Applicant(s)/Patent under Reexamination
10/720,541	KIM ET AL.
Examiner	Art Unit
Jason Heckert	1792

	SEARCHED		
Class	Subclass	Date	Examiner
68	12.05, 12.21	10/25/2007	ЈМН
68	12.27	10/25/2007	ЈМН
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INTERFERENCE SEARCHED			
Class	Subclass	Date	Examiner
68	12.05	10/25/2007	ЈМН
68	12.21	10/25/2007	ЈМН
68	12.27	10/25/2007	ЈМН

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